



Aalto University  
School of Chemical  
Technology

# Spin coating and Langmuir film based deposition techniques

CHEM-L2000

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# Learning objectives

After this lecture the student is able:

- To explain the basic theoretical aspects of spin coating, Langmuir-Blodgett and Langmuir-Schaefer deposition
- To reject a certain film deposition technique based on the knowledge of these coating techniques
- To list which parameters affect specific properties in certain deposition techniques

# Outline

- (1) Spin coating: overview and theory
- (2) Spin coating: pragmatic aspects
- (3) Spin coating: application examples
- (4) Langmuir films: overview and theory
- (5) Langmuir-Blodgett deposition
- (6) Langmuir-Schaefer deposition
- (7) Case studies in Langmuir-Schaefer deposition

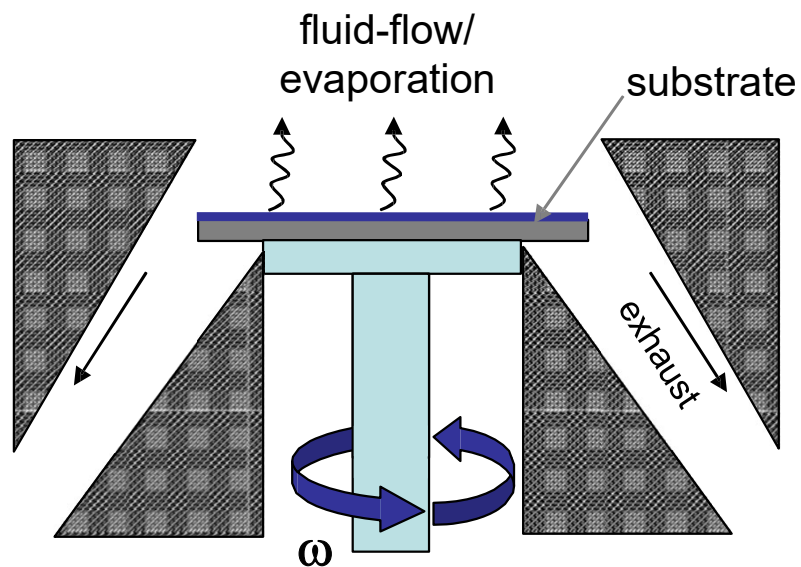
# Spin coating – general issues

(also known as spin casting)

Short description:

A method to prepare films from a dissolved/dispersed substance by removing the solvent with high speed spinning.

Films are usually in the ultrathin regime ( $< 100$  nm).



# Spin coating – general issues

- Used for preparation of ultrathin films with high degree of smoothness
- Widely used
- Totally reproducible
- Also capable of preparing submonolayer “open” films
- Thick films also possible, although with a larger roughness

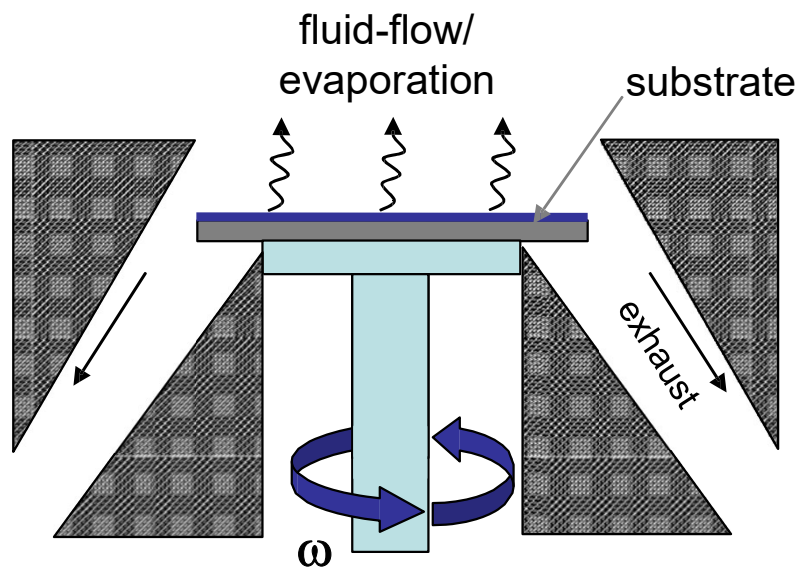
Rule of thumb:

If you can dissolve or disperse a substance, it is possible to prepare a film from it by spin coating.

# Phases of spin coating

# Phases of spin coating

- (1) Spin-up
- (2) Spin-off (fluid flow from the edges of the substrate)
- (3) Evaporation



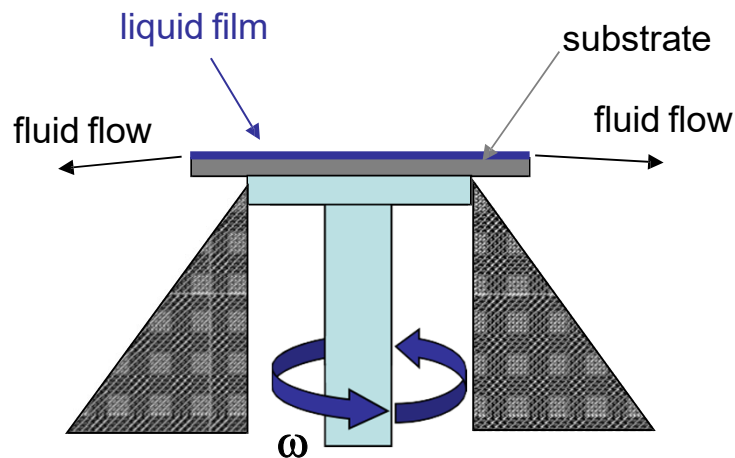
# Phases of spin coating: (I) Spin-up

- The substrate is accelerated to the final rotation speed in 0.5-2 seconds
- Final rotation speeds range from 500-10000 rpm (usual 2000-5000 rpm)
- Spin-up removes most of the solution which has been initially deposited on the substrate (full initial coverage of the solution required)
- Spin-up is the reason why the solution has to wet the substrate (otherwise spin-up would remove all of the solution)



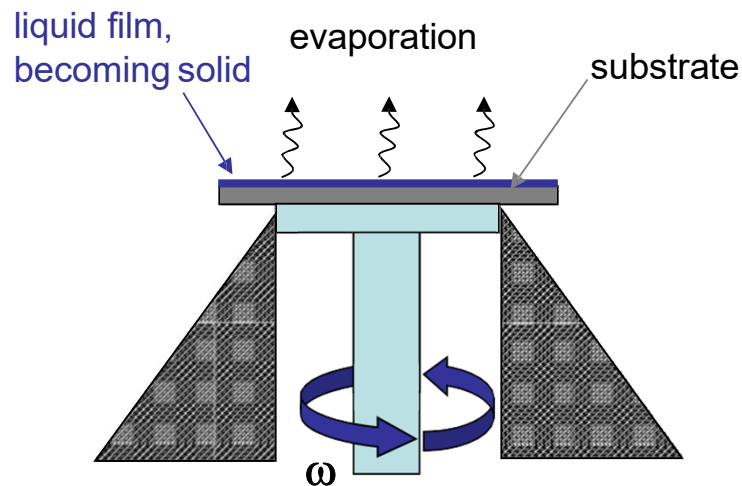
# Phases of spin coating: (II) Spin-off

- Spin-up phase has left a liquid film of  $\sim 100 \mu\text{m}$
- High-speed spinning casts solution off from the edge of the substrate
- Centrifugal rotation forces are balanced by viscous dissipation effect of the solution

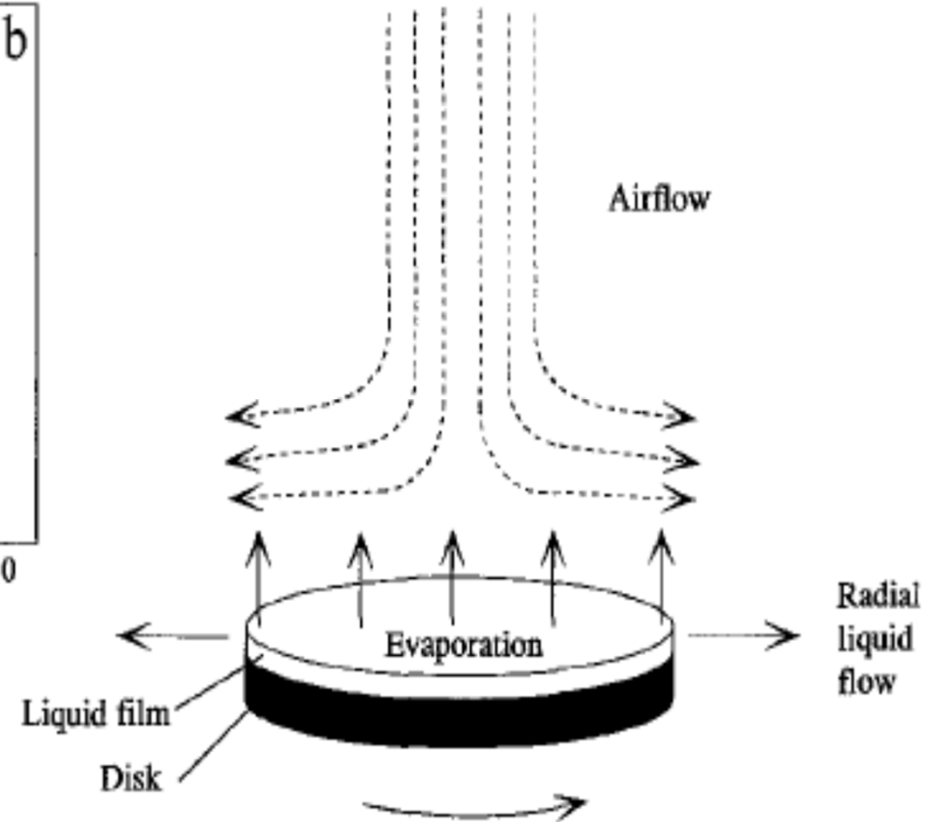
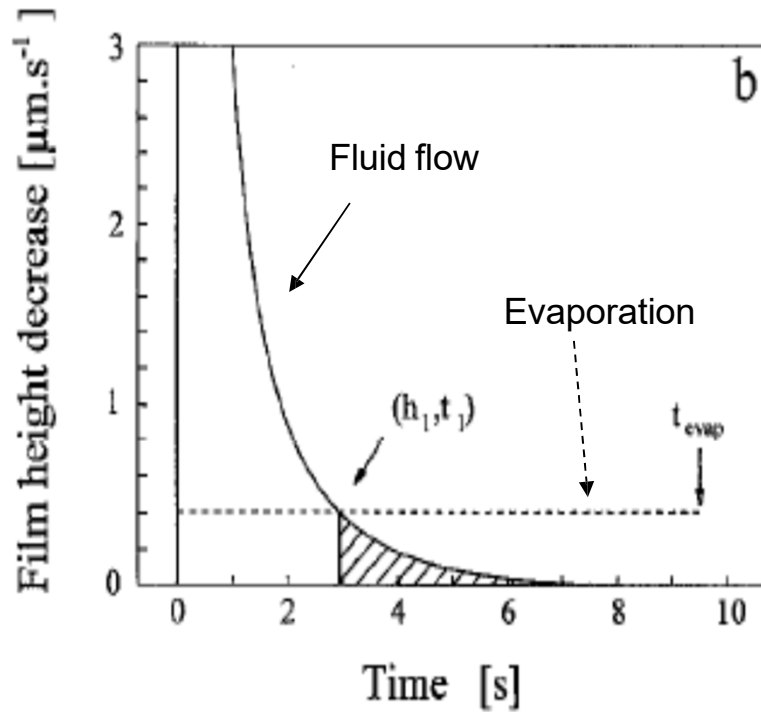


# Phases of spin coating: (III) Evaporation

- After the solvent has been removed to a certain extent in the spin-off stage, the viscosity of the film increases  
→ evaporation starts to remove only the solvent
- Transition between spin-off and evaporation is abrupt
- Evaporation phase does not determine the thickness of the final film because only solvent is removed
- Roughness/smoothness of the final film is largely dictated by evaporation

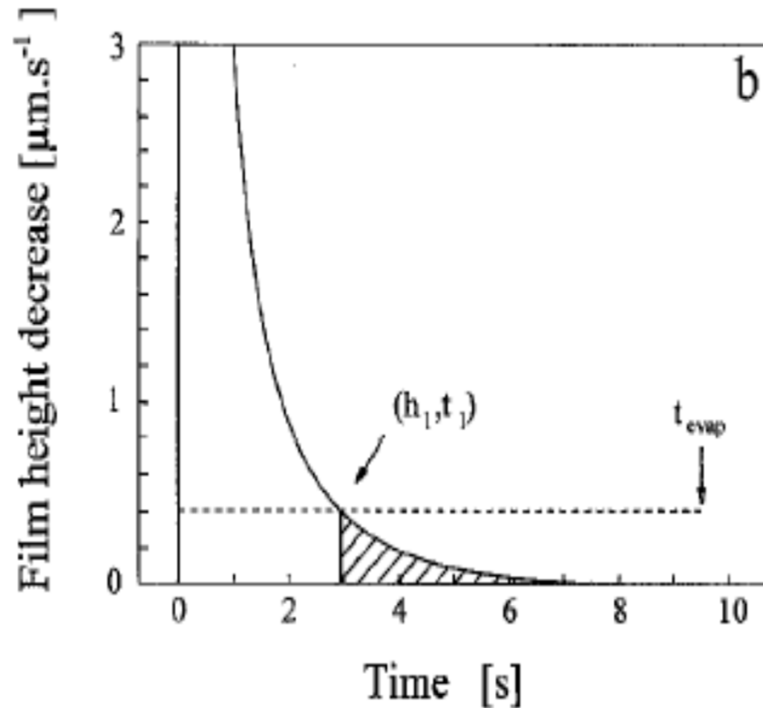


# Fluid flow (spin-off) vs. evaporation



Individual contributions of fluid flow and evaporation on film thickness during spin coating.

# Fluid flow (spin-off) vs. evaporation



$$h_{\infty} \propto \omega^{-1/2} \eta^{1/3} c_0$$

$h_{\infty}$  - film thickness

$\eta$  - viscosity

$\omega$  - spinning speed

$c_0$  - solution concentration

Individual contributions of fluid flow and evaporation on film thickness during spin coating.

# Parameters for spin coating

# Spin coating parameters

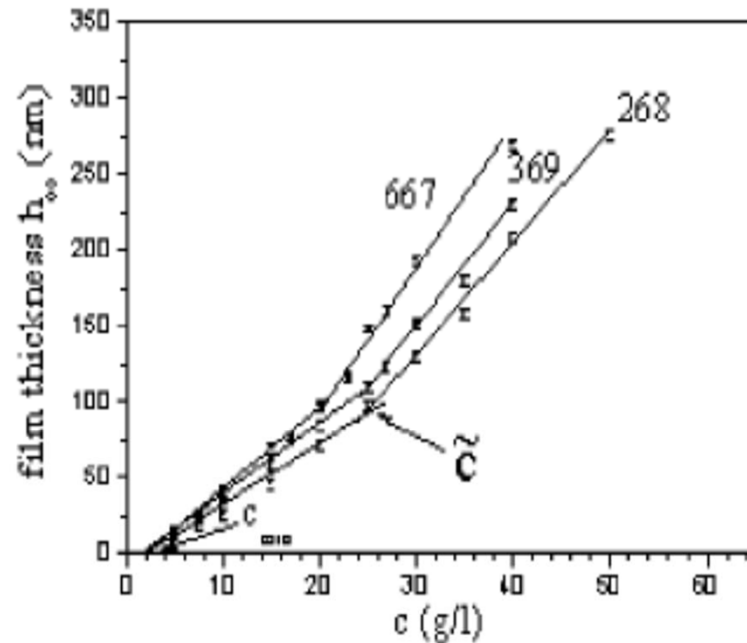
- (1) Initial concentration of the solution
- (2) Molar mass (with polymers only)
- (3) Choice of solvent
- (4) Choice of substrate
- (5) Spinning speed

# Initial solution concentration

$$h_{\infty} \propto \omega^{-1/2} \eta^{1/3} c_0$$

- concentration **largely** determines the film thickness  
→ the larger the concentration, the thicker the film
- concentration also affects the roughness of the film  
→ the larger the concentration, the larger the roughness

# Molar mass and concentration



$$h_{\infty} \propto \omega^{-1/2} \eta^{1/3} c_0$$

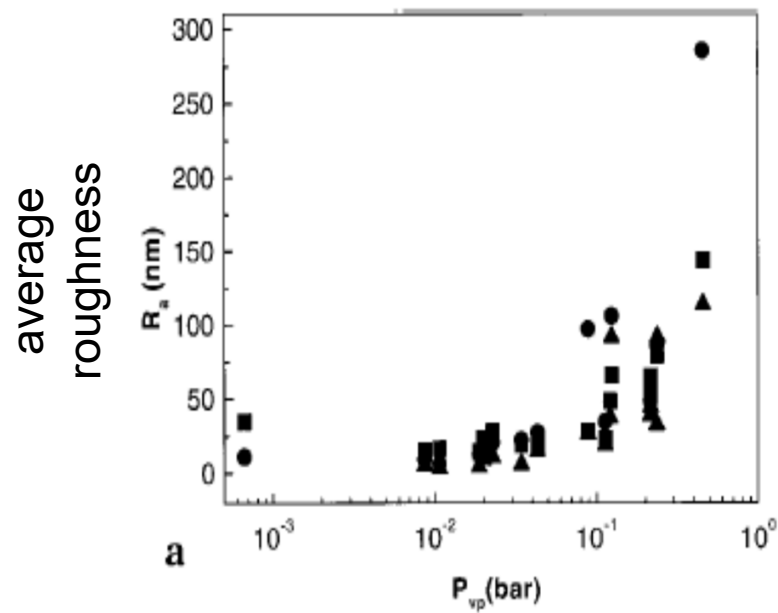
The larger the molar mass, the thicker the film (chain overlap with longer chains amounts to higher thickness)

**Fig. 7** Film thickness as a function of concentration and molar mass. The numbers at the curves indicate the corresponding molar mass in units of kg/mol of the respective polystyrene sample dissolved in toluene.



# Choice of solvent

- The more volatile the solvent, the rougher the film
- Volatile solvents induce so-called Marangoni instability



vapour pressure of the solvent

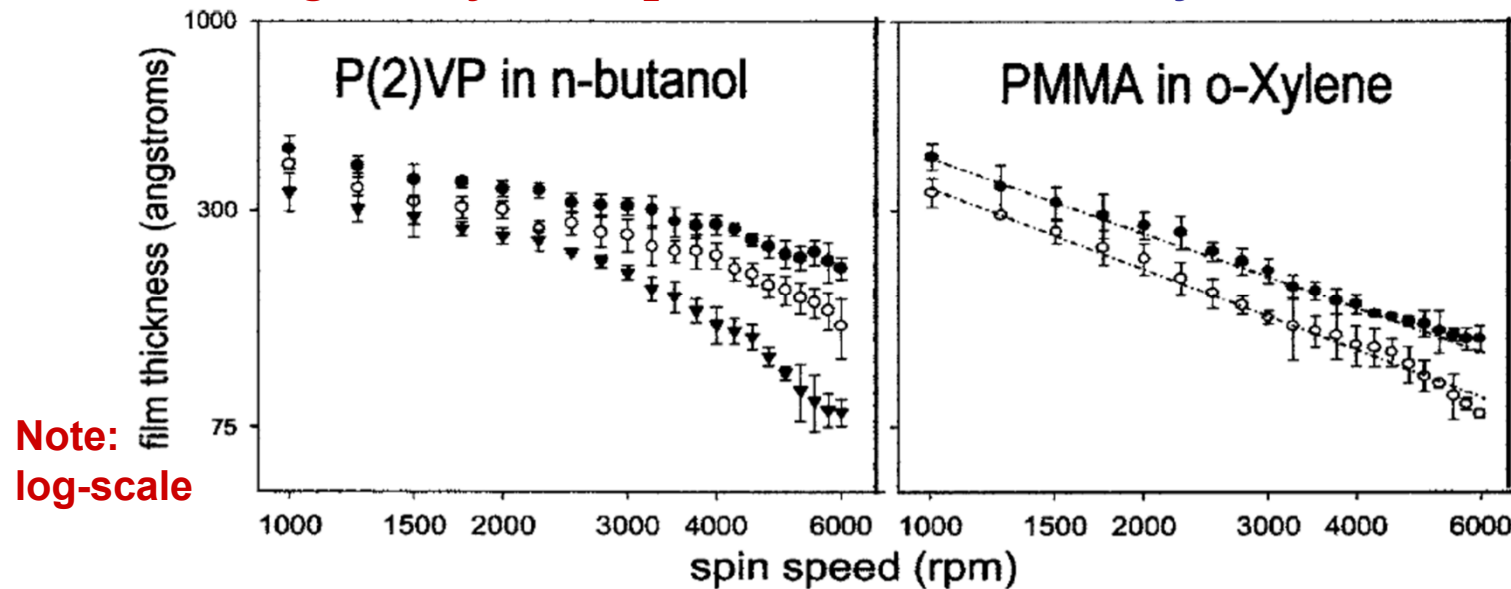
# Choice of substrate

Prerequisite: solvent and substrate have to match, i.e. solvent has to wet the substrate (reasonably low contact angle).

- The affinity of the to-be-coated material towards the substrate has an effect on the film thickness
- An “anchoring polymer” is used sometimes to improve the affinity between the substrate and the coating
- Anchoring polymer does not (usually) affect the film formation as such – it anchors the coating to the surface which prevents the film’s detaching in, e.g., aqueous conditions in the post-treatment stage

# Choice of substrate

**Strong affinity to SiO<sub>2</sub> substrate**    **Weak affinity to SiO<sub>2</sub> substrate**



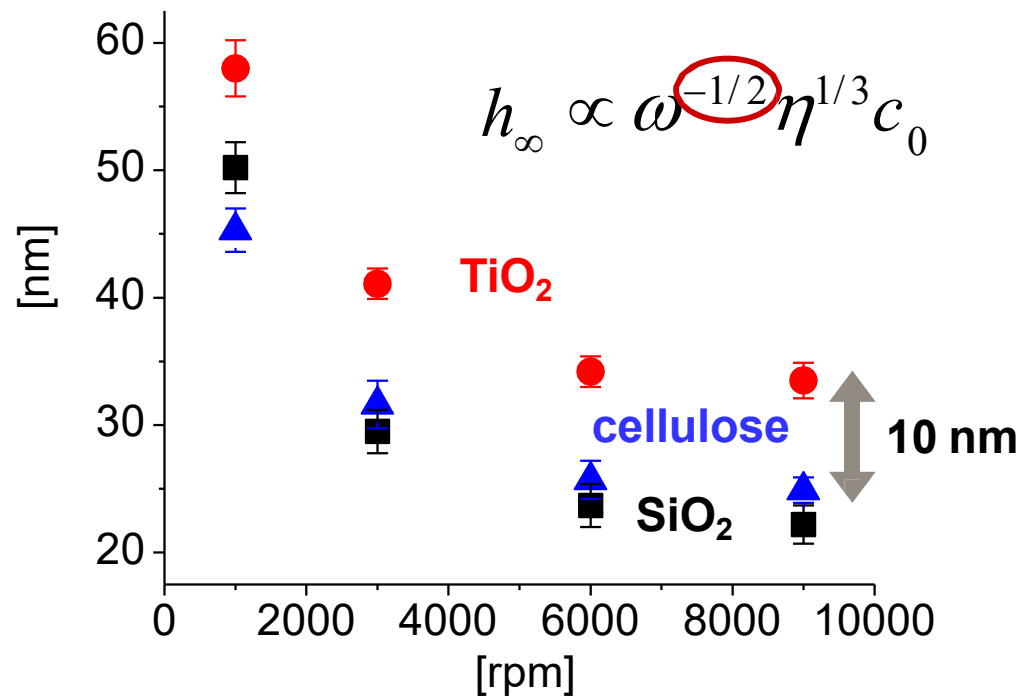
Higher affinity towards the substrate results in a flatter conformation of the polymer.

➔ **Slightly thinner film results.**

Appl. Phys. Lett. **2005**, 87, 214103.

# Choice of substrate

Film of cellulose nanocrystals (anionic) with ~7-8 nm width on different substrates.



## SUBSTRATES:

TiO<sub>2</sub> – cationic

SiO<sub>2</sub> – anionic

cellulose – neutral

Films are apparently monolayer thicker for TiO<sub>2</sub> substrates.



Electrostatic effect.

# Choice of substrate

Submonolayer arrangement of cellulose nanocrystals (anionic in charge)

Concentration of the spin coating solution:

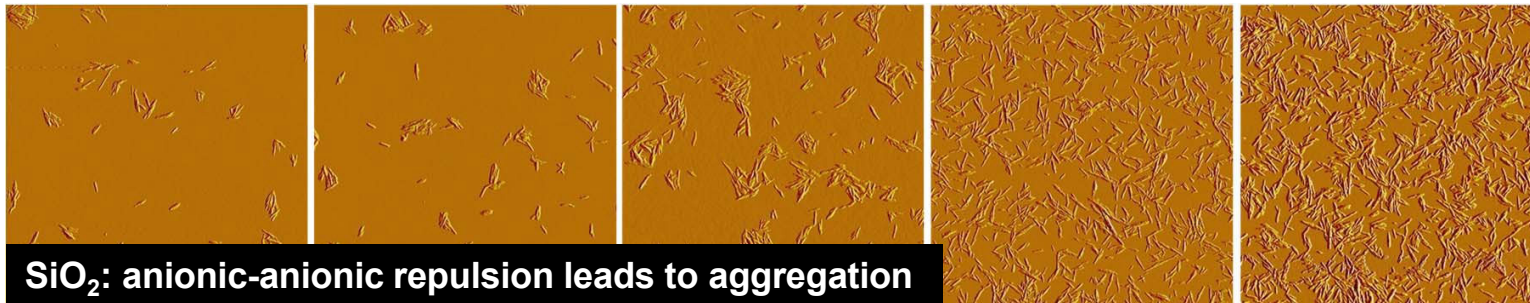
125 mg dm<sup>-3</sup>

250 mg dm<sup>-3</sup>

500 mg dm<sup>-3</sup>

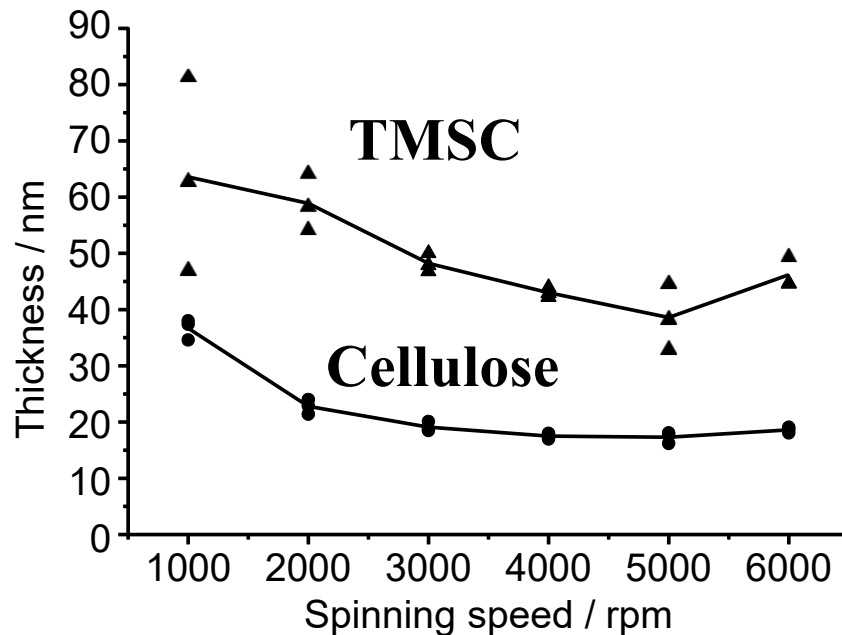
1000 mg dm<sup>-3</sup>

1650 mg dm<sup>-3</sup>

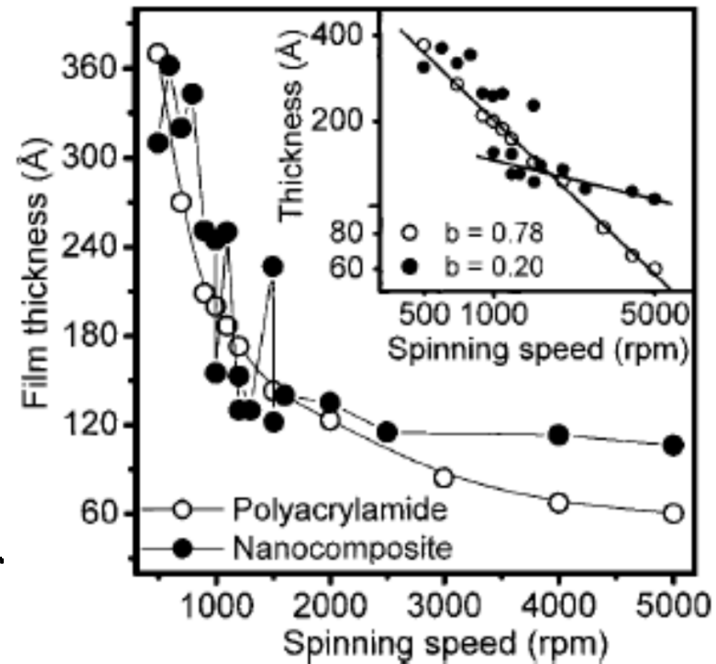


# Spinning speed

- The higher the rotational speed, the thinner the film
- Effect in the “usual” speed regime (2000-5000 rpm) is not remarkable
- Smoothness of the films is also affected by the spinning speed



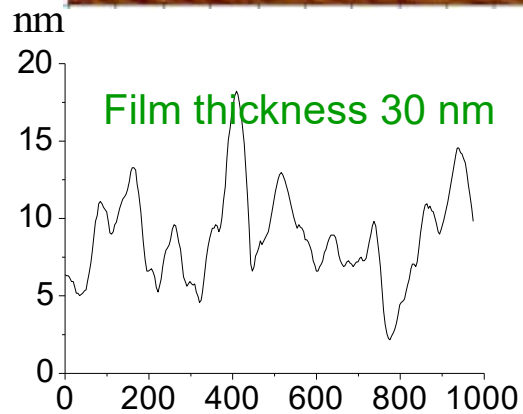
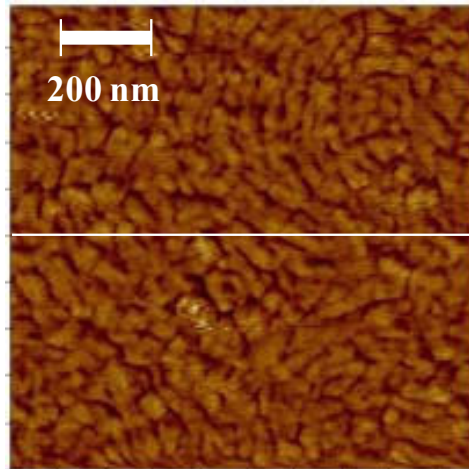
Langmuir **2003**, 19, 5735.



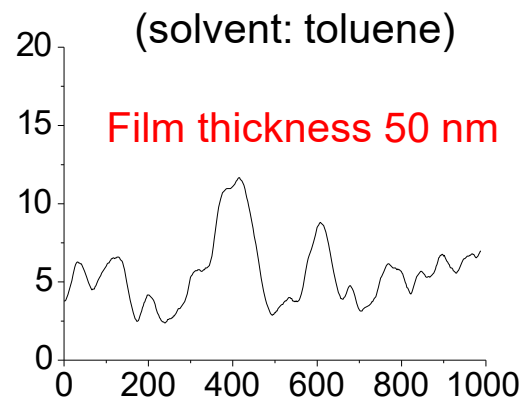
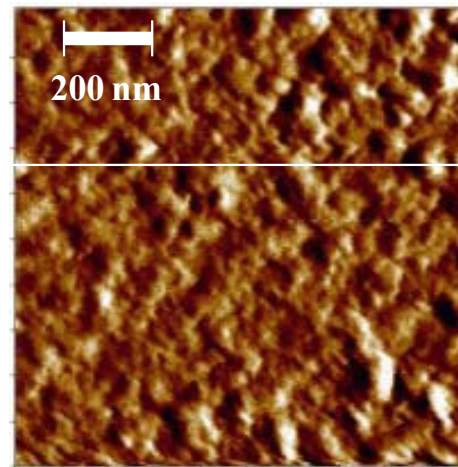
Phys. Rev. E **2004**, 70, 051608.

# Examples on the parameter effect

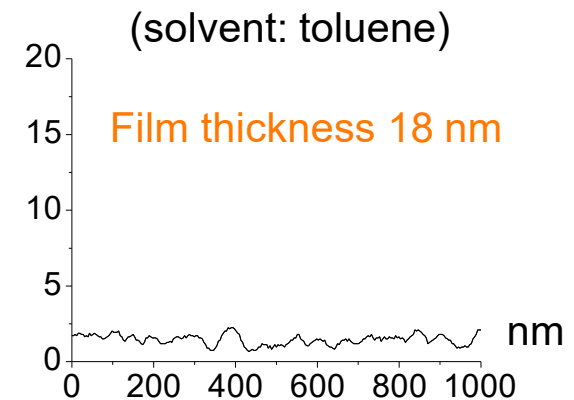
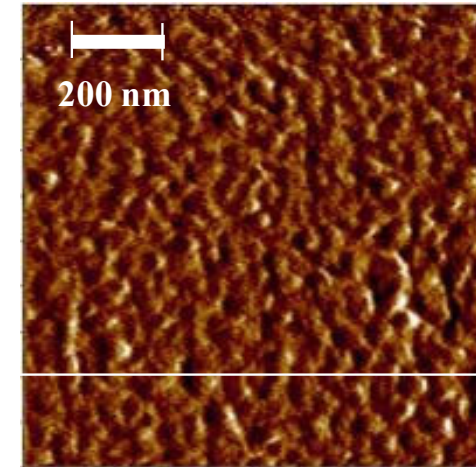
SOLVENT: CHLOROFORM



DOUBLE CONCENTRATION



REFERENCE



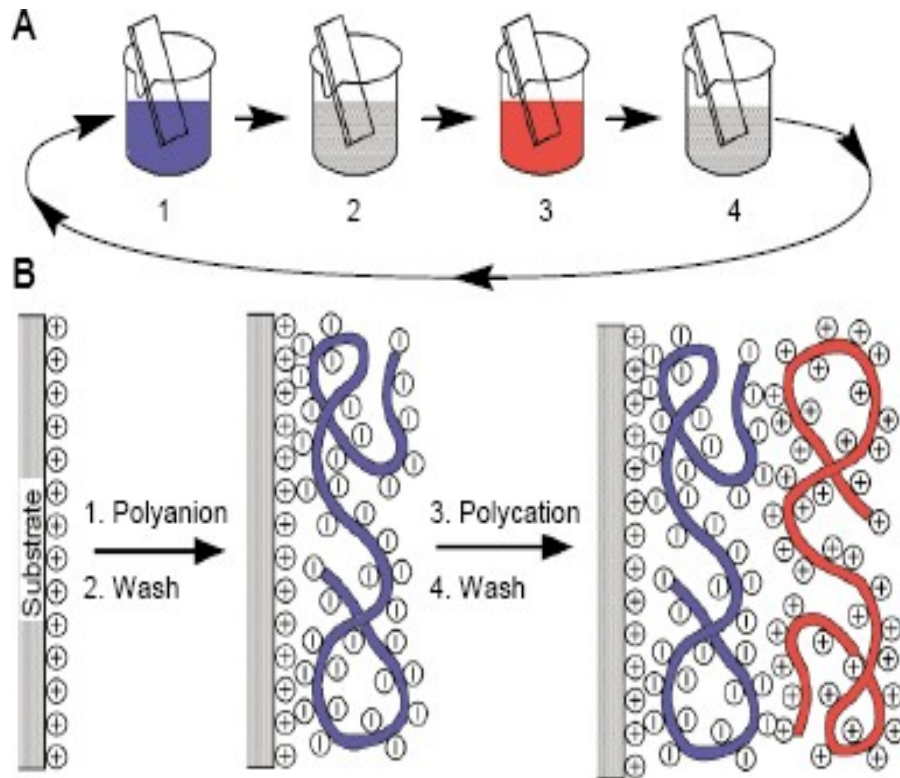
Langmuir 2003, 19, 5735.

# Applications of spin coating – some examples

- (1) Layer-by-layer deposition
- (2) Patterned structures



# Layer-by-layer deposition

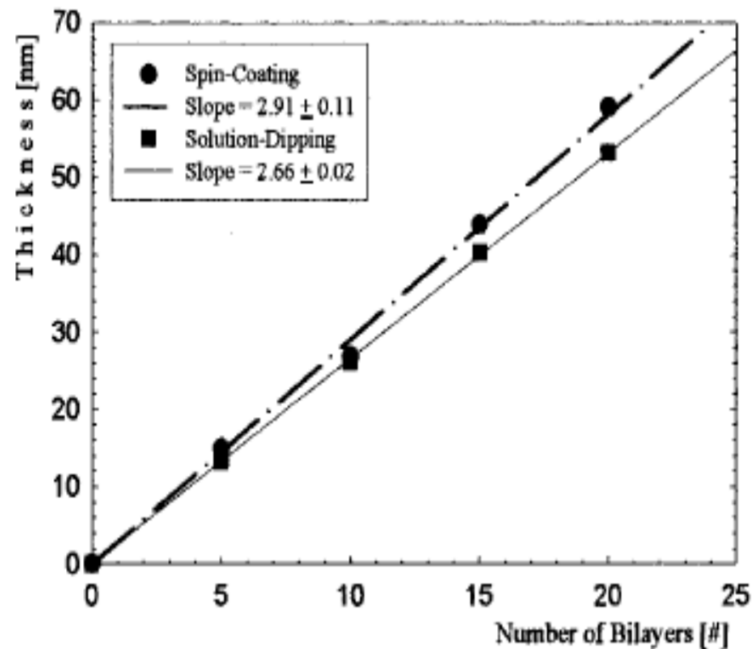


## TRADITIONAL WAY BY ADSORPTION

- Polyelectrolytes of opposite charges can be deposited one after another
- Experimentally a very easy technique: requires only polyelectrolyte solutions and washing in between

Science **1997**, 227, 1232.

# Layer-by-layer deposition by spin coating



## SPIN COATING OFFERS A FASTER WAY

- spin coating can be applied to LbL-deposition, making the process easier and faster
- deposition of one layer takes < 1 min

# Patterned structures – why?

Use of ultrathin films:

**(1) Modelling aspect**

- defined chemistry
- defined morphology

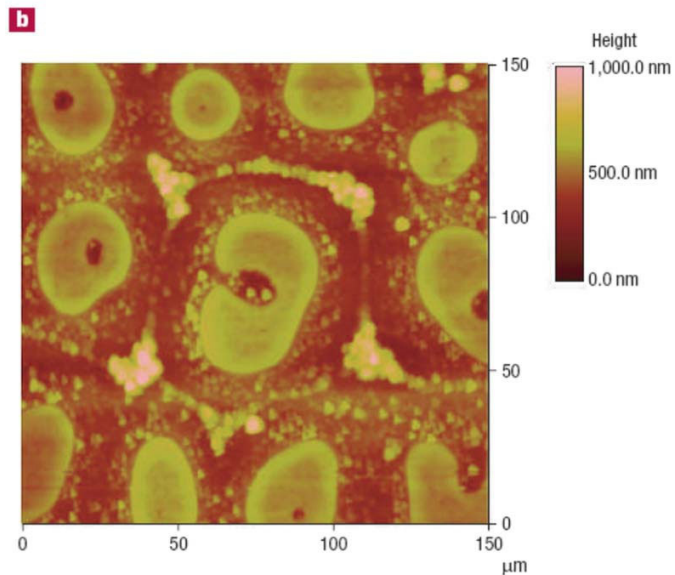
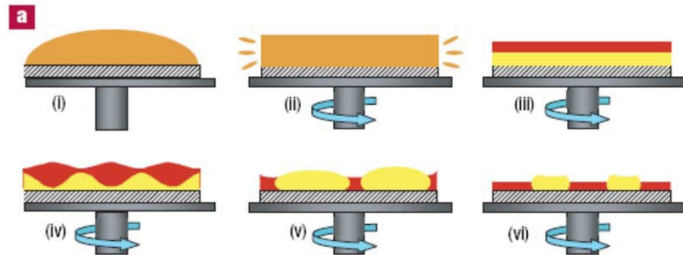
**(2) Functional materials**

- sensors
- transistors
- photonic devices
- receptors
- templates for nanomaterials
- etc.

Often requires patterned structures which can be rather demanding to prepare (microcontact printing etc.).

**Spin coating sometimes offers a quick-and-easy way to patterned structures on ultrathin films.**

# Patterning with polymer blends

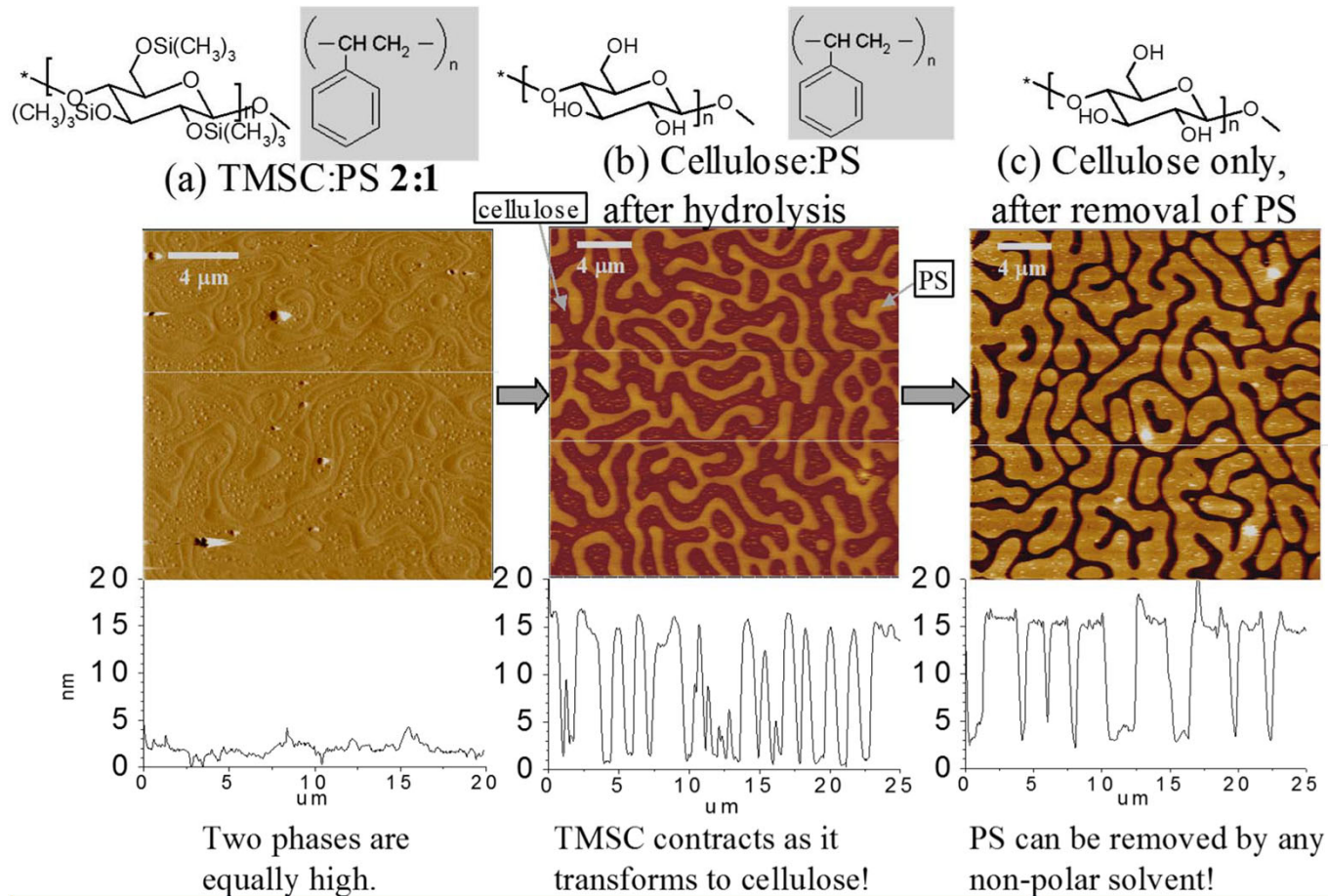


Immiscible polymers  
phase separate  
during spin coating.

- vertical phase separation  
leads to lateral phase  
separation

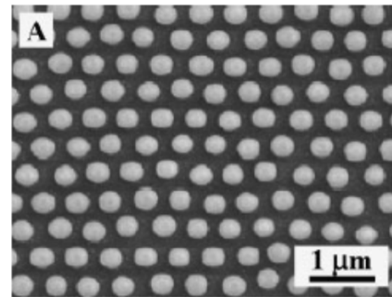
- strong solvent and  
substrate dependence

# Patterning with polymer blends



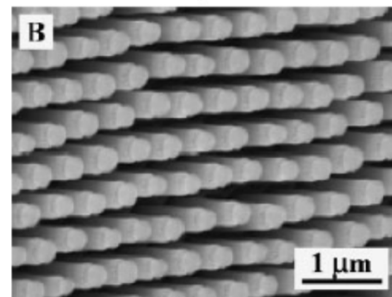
# Ordered silicon pillars as antireflective, self-cleaning coatings

Deposition of hexagonally ordered silica nanoparticles on a silicon wafer by spin coating.

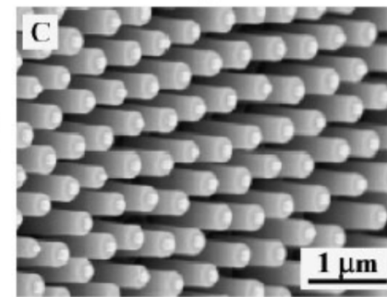


Cl<sub>2</sub> RIE ↓ etching

Silica nanoparticles protect silicon underneath them during etching.  
→ Silicon pillars form.



HF etch →



Impurities are removed.

O<sub>2</sub> RIE ↑

Silica nanoparticles are removed by HF treatment from top of the pillars.

Based on crystallization of colloidal objects during correctly chosen spin coating conditions.

Adv. Mater. 2008, 20, 3914.

# Spin coating - summary

- spin coating is a fast method for preparing smooth ultrathin films
- consists of three phases: (i) spin-up, (ii) spin-off (fluid flow), and (iii) evaporation
- coating solution has to wet the substrate; otherwise no film occurs
- concentration of the coating solution largely determines the film thickness
- use of volatile solvents result in rougher films

# Langmuir-Blodgett deposition

# Langmuir-Schaefer deposition



# Basic idea

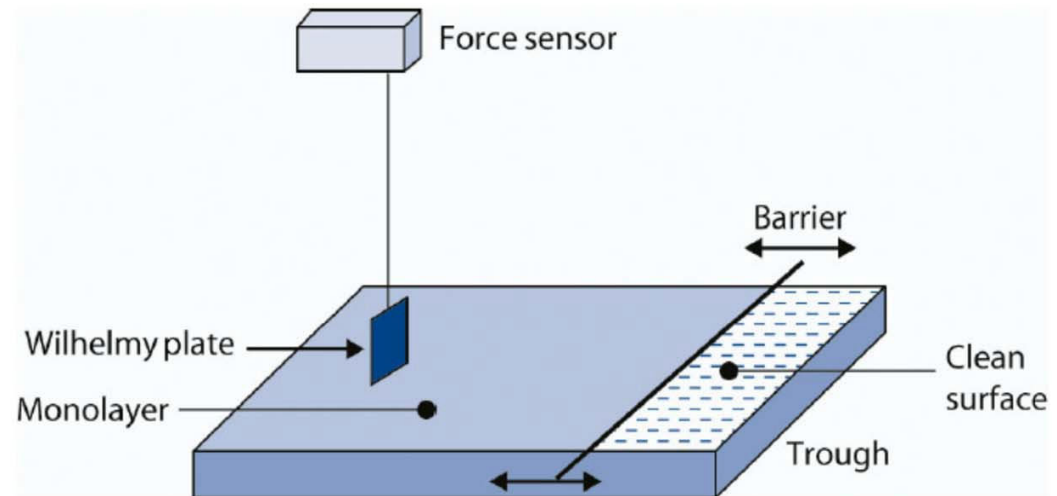
- Immiscible substance or solution is spread on the liquid surface
- The substance forms a film on the liquid surface
- The surface pressure is adjusted mechanically with barriers

- surface pressure

$$\Pi = \gamma_w - \gamma_f$$

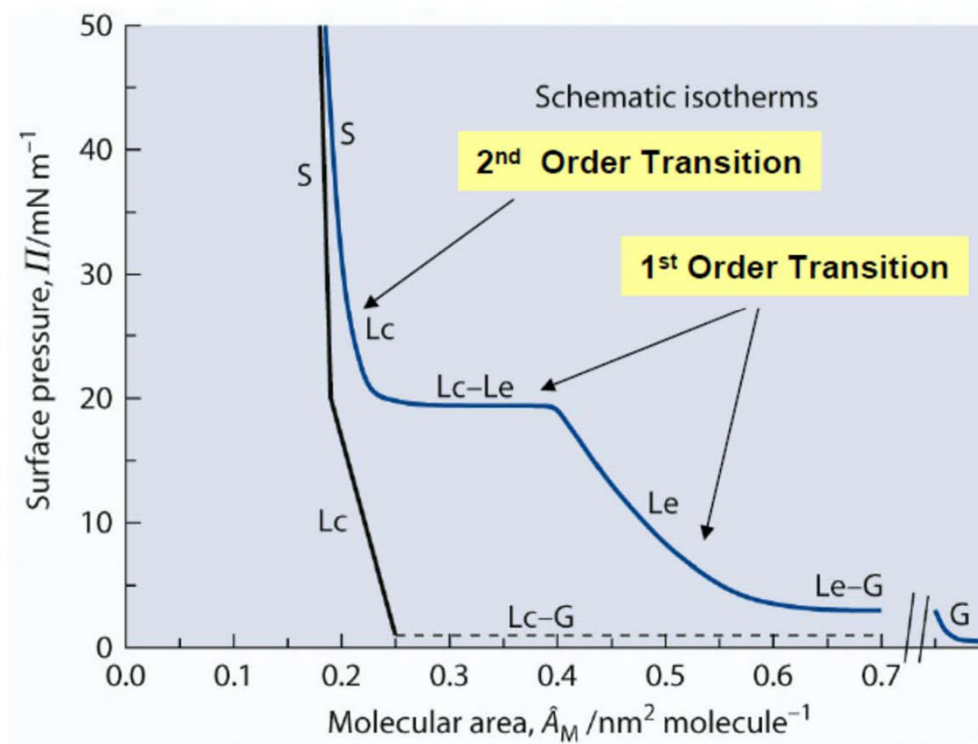
- area per molecule

$$A_M = A / N_M$$



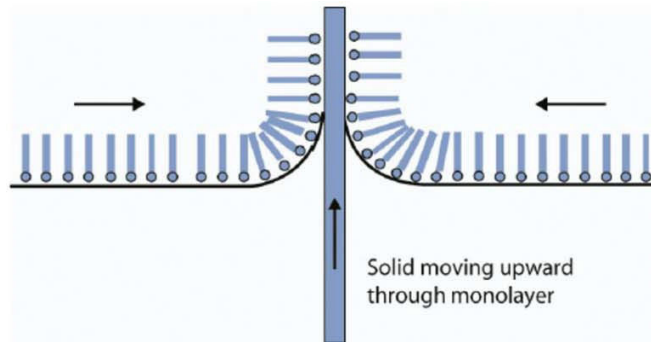
Surface film balance (Langmuir trough)

# Surface pressure isotherms

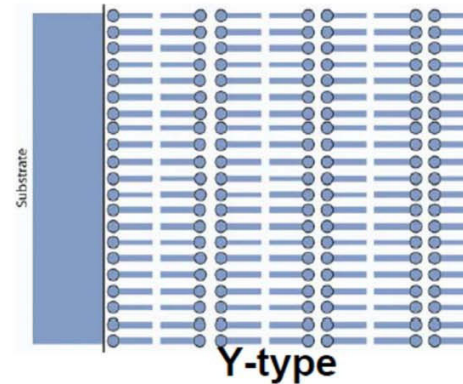
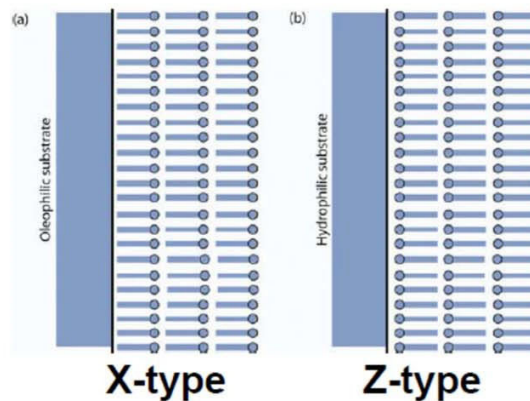


- gaseous phase (G)
- liquid expanded (L<sub>e</sub> or L<sub>1</sub>)
- liquid condensed (L<sub>c</sub> or L<sub>2</sub>)
- Solid phase (S)

# Langmuir-Blodgett deposition

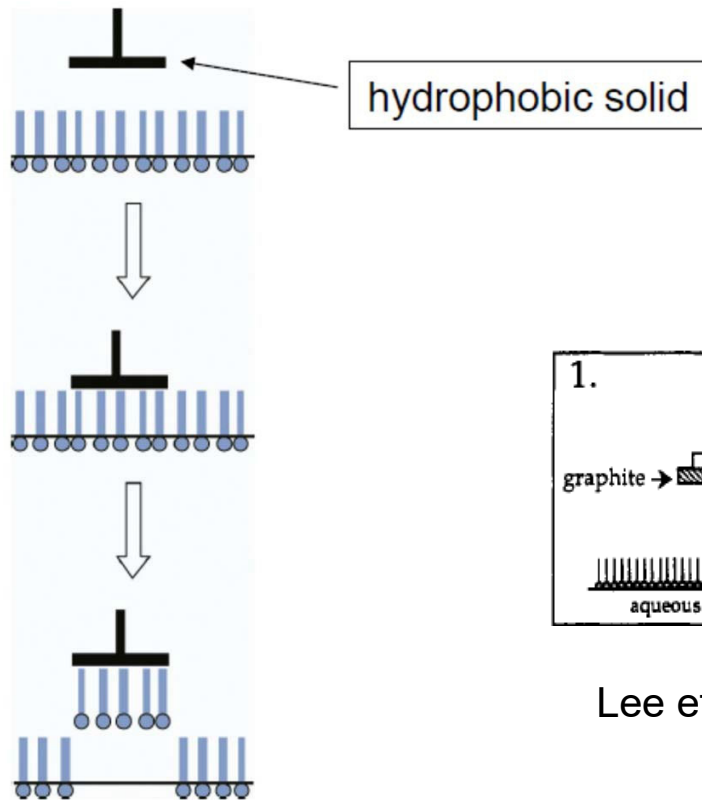


- efficiency of deposition - transfer ratio – ratio of area transferred to the solid to area decrease in the monolayer
- usual substrates (depends on application): mica, silicon, quartz etc.
- film quality depends on pH, ionic strength in subphase

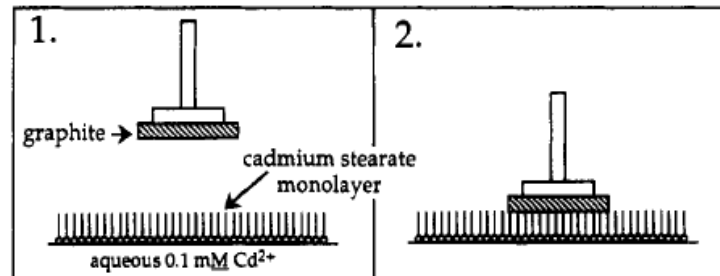


Film thickness is determined by the number of dipping steps.

# Langmuir-Schaefer deposition

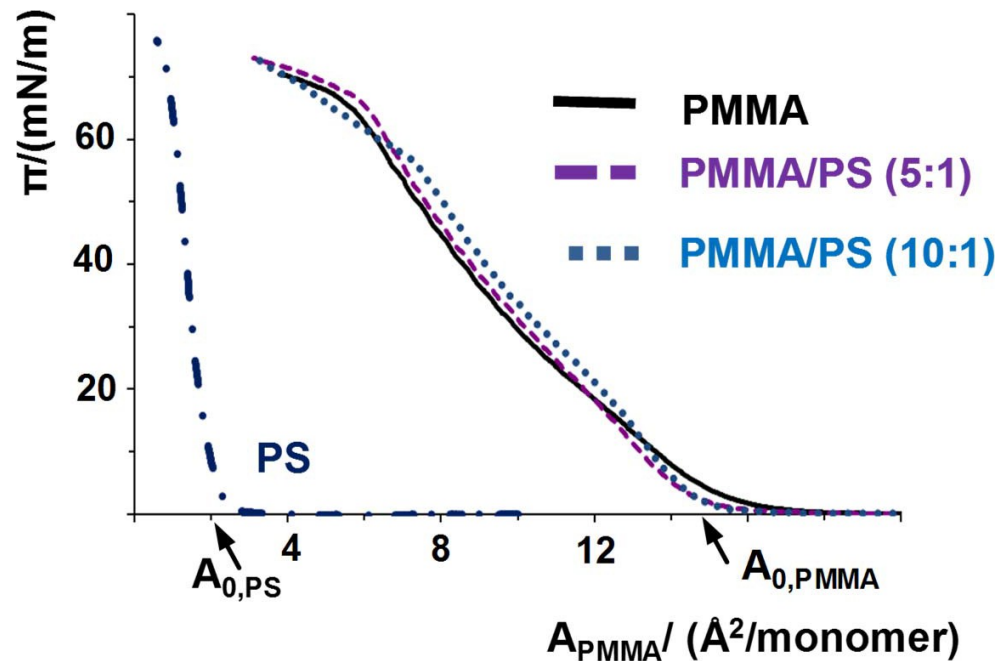


- Horizontal deposition
- Works particularly well for hydrophobic substrates

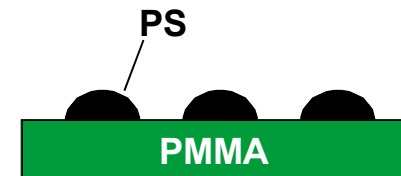


Lee et al. *Langmuir* **1992**, 8, 1243.

# Langmuir-Schaefer deposition: blends

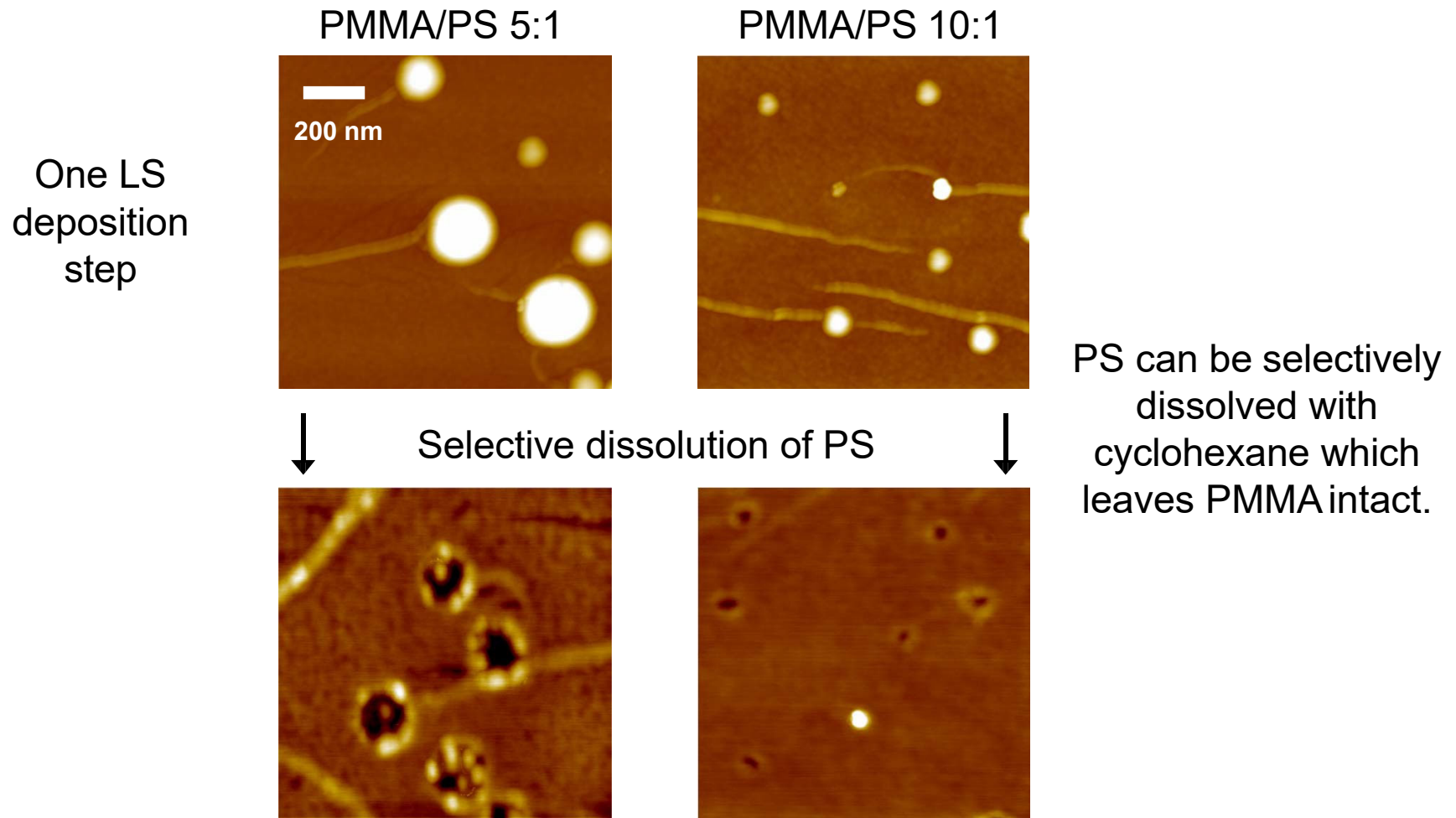


**NOTE.** The surface pressure isotherms have been plotted as a function of a mean molecular area taken by a PMMA monomer.

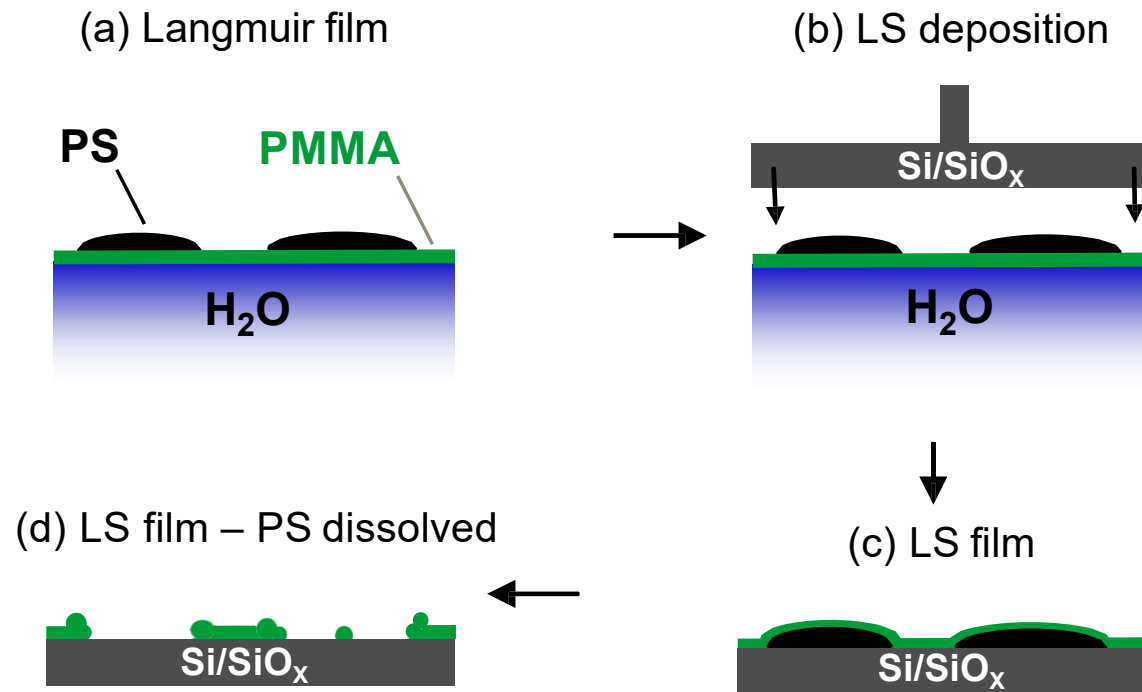


⇒ On a Langmuir film (on water), PMMA appears to form a continuous film with polystyrene on top of it.

# Langmuir-Schaefer deposition: blends

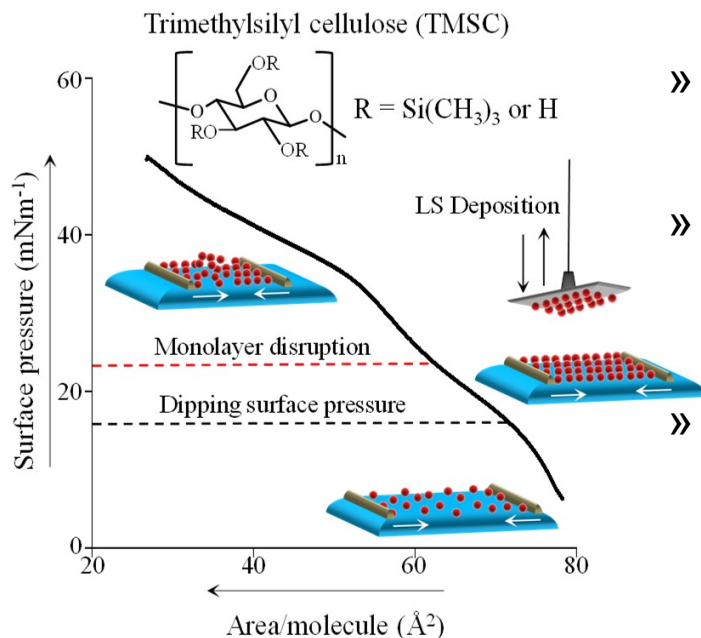


# Langmuir-Schaefer deposition: blends



# Langmuir-Schaefer deposition: substrate effect

## Background

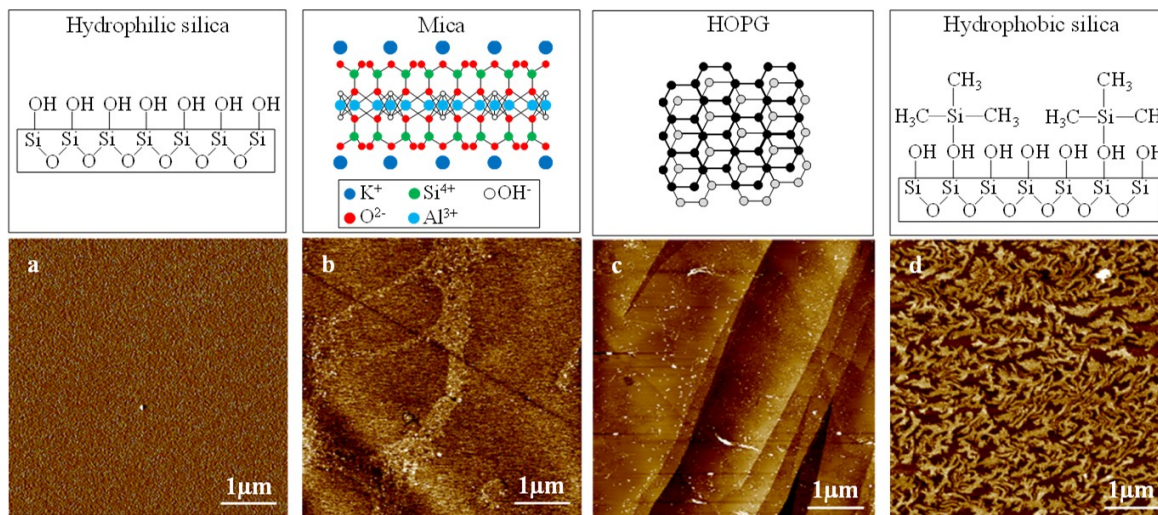
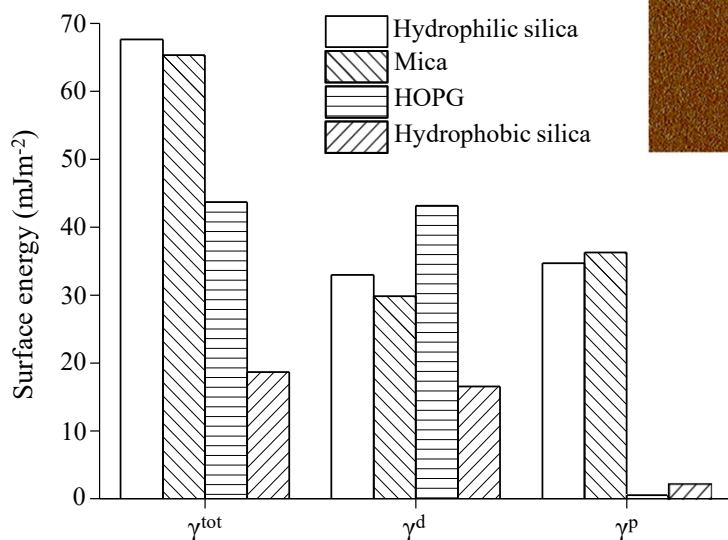


- » 2D patterns becoming more frequent in, e.g., electronic applications or smart materials
- » Cellulose can be used to form 2D morphological patterns
- » Langmuir-Schaefer deposition used to demonstrate 2D fractal patterns using amphiphilic polysaccharide (trimethylsilyl cellulose)
- » Role of supramolecular interplay highlighted using various substrates



# Langmuir-Schaefer deposition: substrate effect

» Morphology of TMSC film can be controlled through supramolecular interactions between polymer and substrate



- » Decrease in total surface free energy shows a shift in film morphology
- » Surface free energy provides indication of supramolecular properties of the substrate surface

# Langmuir film based deposition

- Pure liquid or a solution is spread on a liquid (usually water) surface in a Langmuir trough
- In case of solution, the solvent is allowed to evaporate → Langmuir film
- Surface pressure (film packing) is adjusted with mechanical barriers
- Deposition on a solid substrate by dipping:
  - Vertically in Langmuir-Blodgett deposition
  - Horizontally in Langmuir-Schaefer deposition

# Summary LB and LS deposition

- LB and LS depositions allow highly controlled film growth
- Surface area / pressure isotherms yield additional information on the system

General requirements:

- Coated substance must be soluble/dispersible
- Solvent used for dissolving the coated substance must not be miscible with the lower phase solvent in the Langmuir trough (usually water)
- Coated substance should not be miscible with the lower phase